Contribution ID: 61 Type: not specified

An RF sputtering system for thin film superconducting cavity R&D

Wednesday, 26 August 2015 16:15 (30 minutes)

Here we will outline an RF sputtering system that has recently been installed at UC Berkeley with the goal of developing superconducting thin film cavities for axion searches.

Primary author: SIMANOVSKAIA, Maria (UC Berkeley)

Presenter: SIMANOVSKAIA, Maria (UC Berkeley)

Session Classification: Increasing Cavity Quality Factor